

Colibrys - Equipment for Sale

Asset #	SAP ID	Description / Function / Process	Manufacturer	Model	Serial #	Year	Configuration details	Date available	Available for demonstration	Decommissioned	Crated
	1 AIRCO	Evaporator	Airco Temescal	BJD-1800	282		Rotary holder for 6 4-in wafers or 4 6-in wafers. Planetary holder for 12 4-in wafers. 15 kW e-gun. 6 x 13cc crucible	Immediately	Yes	No	No
22	ETUVE-6	Oven	Heraeus	T5028	8554512		220Vac 1Ph 810W Max: 250°C	Immediately	Yes	No	No
23	ETUVE-7	Oven	Heraeus	T5028	8554511		220Vac 1Ph 810W Max: 250°C	Immediately	Yes	No	No
46	MICROLIT	UV photostabilization system	Fusion Semico	Microlite 150PC	175		Used FUSION 150PC Photoresist Photostabilization System. Fusions rapid, one-step UV/Bake process replaces a standard resist hard bake and allows for higher process margins and increased process consistency. Cassette to cassette handling of wafers up to	Immediately	Yes	No	No
47	MS6210-1	Sputter	Electrotech	MS6210	53		For 4-in wafers and 6-in wafers. 3x12kW power supplies. Sputter Etch. Moving shutter.	Immediately	Yes	No	No
49	NANO-2	Thin film thickness measurement	Nanometrics	Nanospec/AFT	O894H103930003	?	Tabletop film thickness measurement tool with autofocus and programmable mapping stage. 400-900nm range. Single and multilayer film algorithms. Contour and 3D mapping. Wafer sizes 4"-8". 3-60um spot size	Immediately	Yes	Yes	No
116	SIGMA-SC	Step height profilometer	Tencor	SigmaScan 8000100	0583-1084	?	Tencor Sigmascan. Thick film profiler. 65mm scan, auto level. 200A resolution (.02u).	Immediately	Yes	Yes	Yes

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118	WB10	Solvent strip wet bench	RCP	B198	980060	1998		Immediately	Yes	No	No
127	WB9	Solvent strip wet bench	RCP	B197	980059	1998		Immediately	Yes	No	No
472	WB-15	Electroplating wet bench (Au)	Plade		J9175	1999		Immediately	Yes	No	No
474	WB-12	Electroplating wet bench (FeNi, Cu)	Plade		J9174A J9174B	1999		Immediately	Yes	No	No
483	N/A	Laser head for Canon stepper	Canon	Laser head HE-CH Optical unit				Immediately	Spare	Yes	Yes
501	N/A	Precision scale	Mettler-Toledo	PB-303S	112 007 3159	2001	With calibration weights type E2	Immediately	Yes	Yes	No
552	SURFSC-2	Particle counter	KLA-Tencor	Surfscan 5500	9M11707	?	Unpatterned Wafer Surface Inspection Tool, up to 8"/200mm capable. Substrate Thickness: Semi standard thickness. Submicron sensitivity, detects 0.2 micron particles. Surface haze detected as low as 0.3 ppm.	Immediately	Yes	No	No
8264	N/A	Patterned wafer inspection	KLA-Tencor	Surfscan AIT 8010	597-8090	1997	Dual Paddle Robotic Handler - Protective Cover - Stainless Steel external Panels (Skins) - Currently configured for 6-in - Delivered with a calibrated Polystyrene Latex Sphere Contamination Standard	Immediately	No	Yes	Yes
...	ETUVE-12	Oven	SALVIS	TSW 60ED	311074		220Vac 1Ph 1460W Max: 300°C Eshhaust, ventilator	Immediately	Yes	No	No
...	ETUVE-14	Oven	Heraeus	T5042 EK	8002366		220Vac 1Ph 1140W Max: 300°C	Immediately	Yes	No	No
...	N/A	Electroplating power supplies	AMEL	2049	00-0196	Immediately	Yes	Yes	No
	N/A	Electroplating power supplies	AMEL	2049	96038			Immediately	Yes	No	No

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	N/A	Electroplating power supplies	AMEL	2049	96044			Immediately	Yes	No	No
...	N/A	Chillers	Lauda			Immediately	Yes	Yes	No
...	N/A	Autoloaders for Nikon microscopes	Nikon	NWL-640	120377	...		Immediately	Yes	Yes	No
		Autoloaders for Nikon microscopes	Nikon	NWL-640	120372			Immediately	Yes	Yes	No
		Autoloaders for Nikon microscopes	Nikon	NWL-640	120483			Immediately	Yes	Yes	No
		Autoloaders for Nikon microscopes	Nikon	NWL-640	120374			Immediately	Yes	Yes	No
		Autoloaders for Nikon microscopes	Nikon	NWL-641	200639			Immediately	Yes	Yes	No
		Autoloaders for Nikon microscopes	Nikon	NWL-641	200227			Immediately	Yes	Yes	No
...	N/A	Autoloaders for Zeiss microscopes	Zeiss	IM-11	203599	...		Immediately	Yes	Yes	No
N/A	N/A	Scale	Mettler-Toledo	PB-202		Immediately	Yes	Yes	No
8122	1ADE1	Wafer thickness measurement system	ADE	Microsense 6300	3910-0181	...	Non-contact capacitive measurement. Manual loading	Immediately	Yes	Yes	Yes
N/A	N/A	Precision scale	Mettler-Toledo	PJ 3600	L53341			Immediately	Yes	Yes	No
N/A	N/A	Binoculaire	Nikon	Technolook TW-TL10MP	100046			Immediately	Yes	Yes	No
N/A	N/A	Trolley for chemical transfert	Plade	N/A	N/A		Suction from process bath to trolley - Discharge from trolley to drain	Immediately	Yes	Yes	No
N/A	N/A	Trolley for chemical transfert	Plade	N/A	N/A		Suction from process bath to trolley - Discharge from trolley to drain	Immediately	Yes	Yes	No
N/A	N/A	Trolley for chemical transfert	Plade	N/A	N/A		Suction from process bath to trolley - Discharge from trolley to drain	Immediately	Yes	Yes	No
N/A	N/A	Trolley for chemical transfert	Fluidair SA	N/A	N/A		Suction from process bath to trolley - Discharge from trolley to drain	Immediately	Yes	Yes	No
N/A	N/A	Trolley for chemical transfert	Fluidair SA	N/A	N/A		Suction from process bath to trolley - Discharge from trolley to drain	Immediately	Yes	Yes	No

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N/A	N/A	Dewar tank for LN2	Air Liquid	TLC50	N/A		Capacity. 50 liter	Immediatly	Yes	Yes	No
N/A	N/A	Dewar tank for LN2	Air Liquid	TC100	1122		Capacity 100 liter	Immediatly	Yes	Yes	No
N/A	N/A	Dewar tank for LN2	Cryo Diffusion	CT10	432		Capacity 10 liter	Immediatly	Yes	Yes	No
N/A	N/A	Dewar tank for LN2	Cryo Diffusion	CT10	N/A		Capacity 10 liter	Immediatly	Yes	Yes	No
N/A	N/A	Dewar tank for LN4	Cryo Diffusion	L2100	N/A		Capacity 100 liter	Immediatly	Yes	Yes	No
160	-DAGE-1	Shear test	DAGE	BT 2400	940117	1994		Immediatly	Yes	Yes	No